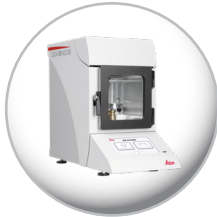


EM Sample Preparation Portfolio

Click on the image buttons to learn more about the individual products

	EM ACE200 > Low vacuum coater > Sputter and carbon coating > Glow discharge for TEM grids		EM TXP > Target preparation system > Sawing, grinding, polishing, milling, core drilling – all in a single self-contained bench top unit > Preparation of buried features and barely visible targets for EM and LM		EM AFS2 > Freeze substitution for transferring high-pressure frozen samples for use at room temperature > Optional: Robotic system for automatic dilution preparation and exchange
	EM ACE600 > High vacuum coater > Sputter, carbon and e-beam coating (various combinations possible) > Glow discharge for TEM grids		EM TIC 3X > Ion beam milling & polishing > Preparation of cross section area with a width of up to 10 mm > Compatible with the transfer shuttle EM VCT500 for inert or cryo-transfer into your electron microscope		EM GP2 > Grid plunger for freezing of samples in liquid ethane or propane > High flexibility: Front or rear blotting and sensor controlled blotting - customized for your sample > Temperature and humidity-controlled sample chamber
	EM CPD300 > Fully automated critical point dryer > Use with ethanol, isopropanol, and acetone > Seamless and efficient drying of samples		UC Enuity > Motorized ultramicrotome > Automated trimming and alignment > Integration of μCT data and fluorescence microscopy		EM VCT500 > Vacuum cryo transfer system > Compatible with your cryo or inert workflow > Contamination-free sample transfer into your electron microscope
	EM TP > Automated tissue processor > Sample preparation (fixation and dehydration) for electron and light microscopy > Reduces manual handling steps by at least 75%		EM ICE (Nano) > High pressure freezer with both light and electrical stimulation > EM ICE Nano: Incubation chamber for physiological atmosphere prior to freezing > Suitable for live cell imaging workflows		EM AC20 > Automatic contrasting of TEM grids and ultra-thin sections > Cost savings due to low reagent consumption



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